The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Previously Presented) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic electroluminescence material; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a pattern of a light emitting layer comprising the organic electroluminescence material over a substrate,

wherein the evaporation cell comprises a tip formed into an orifice.

2. (Previously Presented) A method of manufacturing a light-emitting device, comprising the steps of:

placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a pattern of a light emitting layer comprising the organic electroluminescence material over a substrate by opening and closing the shutter,

wherein the evaporation cell comprises a tip formed into an orifice.

3. (Previously Presented) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic electroluminescence material; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light-emitting device,

wherein the evaporation cell comprises a tip formed into an orifice.

4. (Previously Presented) A method of manufacturing a light-emitting device, comprising the steps of:

placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light-emitting device by opening and closing the shutter,

wherein the evaporation cell comprises a tip formed into an orifice.

5. (Original) A method of manufacturing a light-emitting device as claimed in claim 1, wherein more than one evaporation cell is provided.

6. (Original) A method of manufacturing a light-emitting device as claimed in claim 2, wherein more than one evaporation cell is provided.

7. (Original) A method of manufacturing a light-emitting device as claimed in claim 3, wherein more than one evaporation cell is provided.

8. (Original) A method of manufacturing a light-emitting device as claimed in claim 4, wherein more than one evaporation cell is provided.

9. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

10. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

11. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

12. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

13. (Original) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the organic electroluminescence material is a small molecule material.

14. (Original) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the organic electroluminescence material is a small molecule material.

15. (Original) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the organic electroluminescence material is a small molecule material.

16. (Original) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the organic electroluminescence material is a small molecule material.

17. (Currently Amended) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the ~~organic electroluminescence material is heated in an inert gas atmosphere at an atmospheric pressure~~ inert gas comprises argon.

18. (Currently Amended) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the ~~organic electroluminescence material is heated in an inert gas atmosphere at an atmospheric pressure~~ inert gas comprises argon.

19. (Currently Amended) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the ~~organic electroluminescence material is heated in an inert gas atmosphere at an atmospheric pressure~~ inert gas comprises argon.

20. (Currently Amended) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the ~~organic electroluminescence material is heated in an inert gas atmosphere at an atmospheric pressure~~ inert gas comprises argon.

21. (Previously Presented) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic electroluminescence material;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light emitting device; and

moving the evaporation cell and the substrate relative to each other,

wherein the evaporation cell comprises a tip formed into an orifice.

22. (Previously Presented) A method of manufacturing a light-emitting device, comprising the steps of:

placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light-emitting device by opening and closing the shutter; and

moving the evaporation cell and the substrate relative to each other,

wherein the evaporation cell comprises a tip formed into an orifice.

23. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the evaporation cell is moved.

24. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the evaporation cell is moved.

25. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

26. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

27. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

28. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

29. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

30. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

31. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein a diameter of the orifice is several tens to several hundreds μm.

32. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein a diameter of the orifice is several tens to several hundreds μm.

33. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein a diameter of the orifice is several tens to several hundreds μm.

34. (Previously Presented) The method of manufacturing a light-emitting device according to claim 1 wherein said pattern is directly deposited from said evaporation cell.

35. (Previously Presented) The method of manufacturing a light-emitting device according to claim 2 wherein said pattern is directly deposited from said evaporation cell.

36. (Previously Presented) The method of manufacturing a light-emitting device according to claim 1 wherein said pattern is formed over said substrate without the use of a mask.

37. (Previously Presented) The method of manufacturing a light-emitting device according to claim 2 wherein said pattern is formed over said substrate without the use of a mask.

38. (Previously Presented) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic electroluminescence material, said evaporation cell comprising a tip formed into an orifice adapted to directly deposit a pattern of a light emitting layer comprising the organic electroluminescence material over a substrate; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form the pattern of the light emitting layer comprising the organic electroluminescence material over the substrate.

39. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the evaporation cell is moved.

40. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

41. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein a diameter of the orifice is several tens to several hundreds μm.

42. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the substrate is moved in X-Y directions.

43. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the substrate is moved in X-Y directions.

44. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein the pattern of the light emitting layer has a width of about 50 to 200μm.

45. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein the pattern of the light emitting layer has a width of about 50 to 200μm.

46. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein a pattern of the light emitting layer has a width of about 50 to 200μm.

47. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein a pattern of the light emitting layer has a width of about 50 to 200μm.

48. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein a pattern of the light emitting layer has a width of about 50 to 200μm.

49. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein a pattern of the light emitting layer has a width of about 50 to 200μm.

50. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the pattern of the light emitting layer has a width of about 50 to 200μm.

51. (Previously Presented) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic material,

evaporating the organic material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell;

forming a pattern comprising the organic material over a substrate; and

moving the evaporation cell and the substrate relative to each other,

wherein the evaporation cell comprises a tip formed into an orifice.

52. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein more than one evaporation cell is provided.

53. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

54. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

55. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein the pattern of the light emitting layer has a width of about 50 to 200μm.

56. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein a diameter of the orifice is several tens to several hundreds μm.

57. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein a diameter of the orifice is several tens to several hundreds μm.

58. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein a diameter of the orifice is several tens to several hundreds μm.

59. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein a diameter of the orifice is several tens to several hundreds μm.

60. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein the organic electroluminescence material is ejected through the orifice.

61. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein the organic electroluminescence material is ejected through the orifice.

62. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein the organic electroluminescence material is ejected through the orifice.

63. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein the organic electroluminescence material is ejected through the orifice.

64. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the organic electroluminescence material is ejected through the orifice.

65. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the organic electroluminescence material is ejected through the orifice.

66. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the organic electroluminescence material is ejected through the orifice.

67. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein the organic electroluminescence material is ejected through the orifice.